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Atty Docket No. NOVLP029/NVLS-000495

Application No.: 10/067,520

**Information Disclosure Statement By Applicant** 

Applicant: Shrinivasan et al.

(Use Several Sheets if Necessary)

Filing Date February 5, 2002 Group 2811

# **U.S. Patent Documents**

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# **Other Documents**

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# **U.S. Patent Documents**

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# **Other Documents**

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